

(12) United States Patent Hsu et al.

(10) Patent No.: US 8,536,660 B2

(45) Date of Patent:

Sep. 17, 2013

(54) HYBRID PROCESS FOR FORMING METAL GATES OF MOS DEVICES

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(*) Notice: Subject to any disclaimer, the term of this

patent is extended or adjusted under 35 U.S.C. 154(b) by 844 days.

(21) Appl. No.: 12/047,113

(22) Filed: Mar. 12, 2008

Prior Publication Data (65)

> US 2009/0230479 A1 Sep. 17, 2009

(51) Int. Cl. H01L 21/02

(2006.01)

(52) U.S. Cl.

USPC 257/410; 257/E29.137

(58) Field of Classification Search

USPC 257/369, 371, 374, 410, 411, 412, 257/E27.064, E27.067, E27.108, E29.128,

See application file for complete search history.

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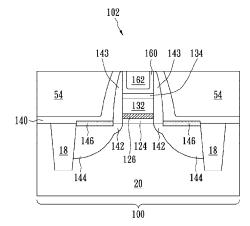
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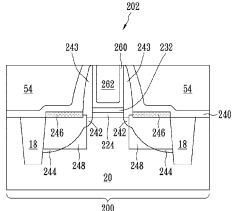
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ABSTRACT

A semiconductor structure includes a first MOS device including a first gate, and a second MOS device including a second gate. The first gate includes a first high-k dielectric over a semiconductor substrate; a second high-k dielectric over the first high-k dielectric; a first metal layer over the second high-k dielectric, wherein the first metal layer dominates a work-function of the first MOS device; and a second metal layer over the first metal layer. The second gate includes a third high-k dielectric over the semiconductor substrate, wherein the first and the third high-k dielectrics are formed of same materials, and have substantially a same thickness; a third metal layer over the third high-k dielectric, wherein the third metal layer and the second metal layer are formed of same materials, and have substantially a same thickness; and a fourth metal layer over the third metal layer.

17 Claims, 11 Drawing Sheets





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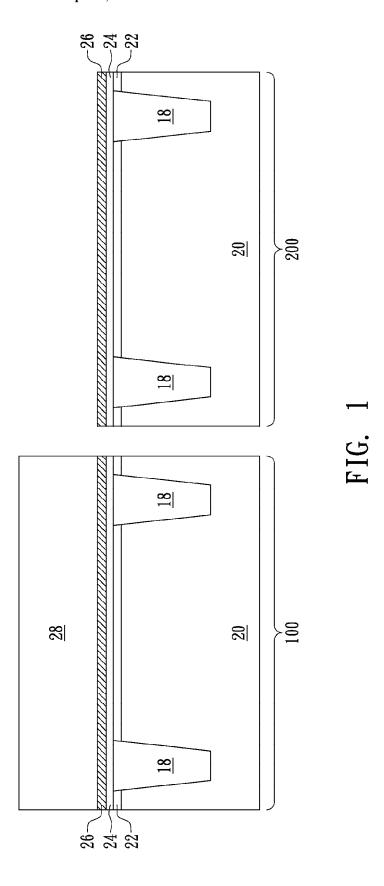


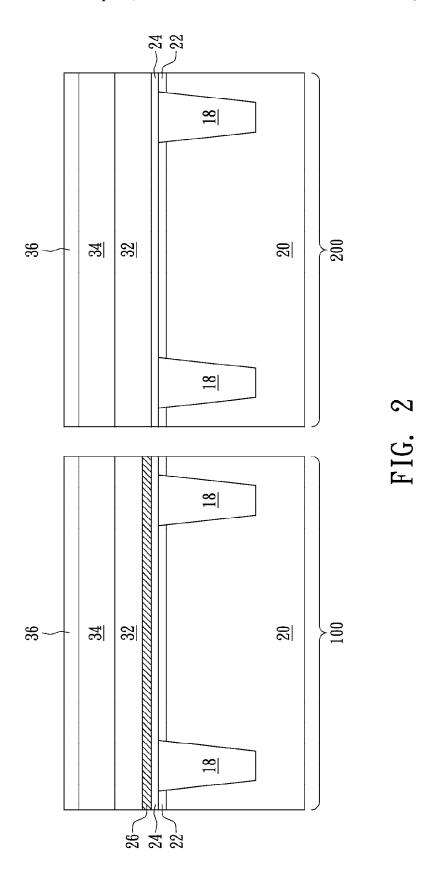
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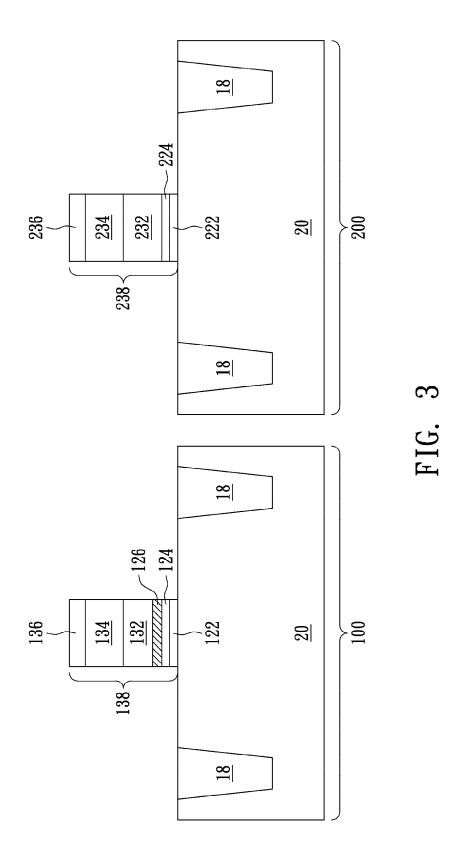
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